

## WEST Search History





DATE: Monday, February 13, 2006

Hide?	<u>Set</u> <u>Name</u>	<u>Query</u>	<u>Hit</u> <u>Count</u>
		<i>DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L7	L6 same ((chamber or apparatus) adj5 (clean\$3 or etch\$3 or treat\$3))	62
<input type="checkbox"/>	L6	(semiconductor or substrate or workpiece or wafer) with (clean\$3 or treat\$3 or etch\$3) with (hydrogen or 'H.sub.2') with plasma	722
		<i>DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L5	L4 and l3	10
<input type="checkbox"/>	L4	134/1,1.3,21,21.1,26,30,902;438/905,906.ccls.	8260
<input type="checkbox"/>	L3	l2 with argon	197
<input type="checkbox"/>	L2	(semiconductor or substrate or workpiece or wafer) with (clean\$3 or treat\$3 or etch\$3) with (hydrogen or 'H.sub.2') with plasma	1542
<input type="checkbox"/>	L1	(semiconductor or substrate or workpiece or wafer) with (clean\$3 or treat\$3 or etch\$3) with (hydrogen or 'H.sub.2O' with plasma)	8361

END OF SEARCH HISTORY

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Hide?	<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>
	<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L17	L16 and (((probe or transmit\$3 or transduc\$3) with vibrat\$3 with energ\$5) same ((wafer or substrate or workpiece) with rotat\$3))	3
<input type="checkbox"/>	L16	L15 or l14 or l13 or l12 or l11 or l10	142227
<input type="checkbox"/>	L15	(samsung electronics co).as.	141369
<input type="checkbox"/>	L14	jo-hyun\$.in.	38
<input type="checkbox"/>	L13	nam-jeong\$.in.	90
<input type="checkbox"/>	L12	kim-kyung\$.in.	967
<input type="checkbox"/>	L11	yoon-byoung\$.in.	53
<input type="checkbox"/>	L10	yeo-in\$.in.	86
	<i>DB=USPT,USOC; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L9	((probe or transmit\$3 or transduc\$3) with vibrat\$3 with energ\$5) same ((wafer or substrate or workpiece) with rotat\$3)	28
	<i>DB=PGPB; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L8	((probe or transmit\$3 or transduc\$3) with vibrat\$3 with energ\$5) same ((wafer or substrate or workpiece) with rotat\$3)	10
	<i>DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L7	((probe or transmit\$3 or transduc\$3) with vibrat\$3 with energ\$5) same ((wafer or substrate or workpiece) with rotat\$3)	38
	<i>DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L6	((probe or transmit\$3 or transduc\$3) with vibrat\$3 with energ\$5) same ((wafer or substrate or workpiece) with rotat\$3)	2
<input type="checkbox"/>	L5	((probe or transmit\$3 or transduc\$3) with vibrat\$3) same ((wafer or substrate or workpiece) with rotat\$3)	45
<input type="checkbox"/>	L4	probe with vibrat\$3 with (wafer or substrate or workpiece) with rotat\$3	0
	<i>DB=USPT,USOC; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L3	probe with vibrat\$3 with (wafer or substrate or workpiece) with rotat\$3	14
	<i>DB=PGPB; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L2	probe with vibrat\$3 with (wafer or substrate or workpiece) with rotat\$3	12
	<i>DB=USPT; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L1	6039059.pn.	1

END OF SEARCH HISTORY